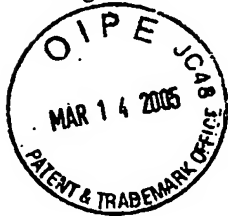


PATENT APPLICATION

Atty. Docket No.: 2522-042 Serial No.: 10/734,479  
 Applicant: Eun-Taek KIM, et al.  
 Filing Date: December 12, 2003 Group: 1746



INFORMATION DISCLOSURE CITATION  
 FORM PTO-1449 (Modified)

U.S. PATENT DOCUMENTS

Exam Init	Ref	Document Number	Issue Date	Name	Class	Sub Class
_____	_____					

FOREIGN PATENT DOCUMENTS

Exam Init	Ref	Document Number	Publication Date	Country	Name
<u>SA</u>	_____	09-148255	June 6, 97	Japan	Tomomi, et al.
<u>SA</u>	_____	11-222679	Aug. 17, 99	Japan	Toshiyuki, et al.
<u>SA</u>	_____	2000-143213	May 23, 00	Japan	Chitoshi, et al.

OTHER DOCUMENTS

Exam Init	Ref	Author, Title, Date, Pertinent Pages, Etc.)
<u>SA</u>	_____	English language abstract of Japanese Publication No. 09-148255
<u>SA</u>	_____	English language abstract of Japanese Publication No. 11-222679
<u>SA</u>	_____	English language abstract of Japanese Publication No. 2000-143213


Examiner: Schano Y

Date Considered: 3/24/06


Applicant: Eun-Taek Kim, et al.  
Filing Date: December 12, 2003 Art Unit: not yet assigned  
Serial No. not yet assigned Examiner: not yet assigned  
Title: METHOD FOR CLEANING A DEPOSITION CHAMBER AND DEPOSITION  
APPARATUS FOR PERFORMING IN SITU CLEANING.

INFORMATION DISCLOSURE CITATION  
FORM PTO-1449 (Modified)

FOREIGN PATENT DOCUMENTS

Exam Init	Ref	Document Number	Publication Date	Country	Name
	—	JP11222679	8/17/1999	Japan	Toshiyuki et al.

OTHER DOCUMENTS

Exam Init	Ref	Author, Title, Date, Pertinent Pages, Etc.)
	—	English language Abstract from Japanese Patent Publication No. JP11222679 published 8/17/1999.

Examiner: 

Date Considered: 